### EM Effects on Semiconductor Devices, Gates and Integrated Circuit Interconnects

Dept. of Electrical and Computer Engineering, UMCP

#### **Neil Goldsman**

Collaborators: Omar Ramahi, John Rodgers Xi Shao, Parvez N. Guzdar<sup>4</sup> Akin Akturk, Zeynep Dilli, Bo Yang, Lattise Parker, Todd Firestone

### Outline

EM Coupling: Levels Investigated Task 1: Device Level Task 2: Gate Level (Inverters) Task 3: Interconnects and Passive Elements

#### **CMOS INVERTER**



#### MOSFET Cross-Section and Illustration of Vulnerabilities: Oxide and Avalanche Breakdown



#### Problems:

-Scaling to the nanometer gate length requires oxides less than 20Angstroms.

-Such thin oxides give rise to such large gate current that devices will not function. -Large internal fields cause impact ionization, avalanching and damaging filaments -Problems especially important for EM coupling, which can induce large voltages to Gate and Drain Electrodes!

#### Developed Quantum Device Simulator to Investigate Internal MOSFET Subject to Large Coupled EM Terminal Voltages

Solve QM Device Equations Numerically. Inputs are device structure, doping profile & basic physics.



#### Device Doping Profile



Electron Transport Physics Include: -Acoustic & Optical Phonons

- -Band Structure
- -Ionized Impurities
- -Impact Ionization & Breakdown
- -Surface Roughness
- -Gate Current and Oxide Breakdown

#### Quantum Device Modeling Gives Internal Fields, Currents and Problem Spots:

#### x 10<sup>27</sup> Impact Generation Rate (1/cm<sup>3</sup>/sec) 10<sup>-6</sup> Vd=2.25V /d=2.0\ 10<sup>-8</sup> Vd=1.75V Vd=1.5V (€) g 10<sup>-1</sup> 10 0.5 0.5 0 1.5 10<sup>-14</sup> -0.5 SH EXP 2 -1 Depth (µm) Lateral (µm) 0.5 1.5 2.5 0 2 Vg (V)

Internal MOSFET Avalanche Rate

Using the new simulator to model EM induced avalanche breakdown

- -Results indicate 2V on drain of  $0.1 \mu m$  causes excessive electron-hole pair generation peak in channel.
- -Simulations agree with experiment on resulting substrate current
- -Excessive substrate current causes permanent filament damage

#### Resulting Parasitic Substrate Current

#### **Gate Current: Mathematical Model**

The final gate leakage current will be the summation of the tunneling and thermionic current

 $J_{gate}(x) = J_{th}(x) + J_{th}(x)$ Where tunneling current

 $J_{tu}(x) = \int_{0}^{E_{peak}} f(\xi, x) g(\xi) v_{\perp}(\xi) T_{tun}(\xi, x) d\xi$ And thermionic<sup>0</sup> current

$$J_{ther}(x) = \int_{E_{peak}}^{\infty} f(\xi, x) g(\xi) v_{\perp}(\xi) T_{ther}(\xi, x) d\xi$$



 $J_{gate} = Gate Current Density$  f = Distribution Function g = Density of States  $T_{tu} = Tunneling Probability$  $T_{ther} = Thermionic Probability$ 

#### Boltzmann-Schrodinger/Spherical Harmonic Device CAD Results: Gate Current (WKB Method): Degrades Device



#### Resulting Electrostatic Potential inside 0.14µm MOSFET: Bias Conditions for Oxide Breakdown



 $V_G=2.8V$   $V_D=1.4V$   $V_S=V_B=0V$ If  $|E_y| > 7MV/cm => Oxide Breakdown$ 

Device Simulations predicts induced gate voltage of 2X supply causes MOSFET oxide damage

# Task 2. EM Effects on Gates

Differential equation based modeling of EM effects on inverter circuits

- Stage 1: Develop simulation tool.
- Stage 2: Use tool to analyze distributed effects of EM GHz range coupling on fundamental computer chip circuit elements.

#### Developed Distributed Circuit Simulator Applied to Inverters

**DD** Equations

$$\nabla^2 \phi = -\frac{q}{\varepsilon_{Si}} (p - n + D)$$

$$\frac{\partial n}{\partial t} = \frac{1}{q} \nabla . \overrightarrow{J_n} - R_n + G_n$$
$$\frac{\partial p}{\partial t} = -\frac{1}{q} \nabla . \overrightarrow{J_p} - R_p + G_p$$

**Supplementary DD Equations** 

$$\overrightarrow{J_n} = -q\mu_n n \overrightarrow{\nabla \Phi} + q\mu_n V_T \overrightarrow{\nabla n}$$
$$\overrightarrow{J_p} = -q\mu_p p \overrightarrow{\nabla \Phi} - q\mu_p V_T \overrightarrow{\nabla p}$$

**Coupled Discretized DD Equations are solved at each mesh point** 





CMOS Inverter (CMI)

Lumped KCL equation check at the output node and using the KCL equation, the output guess is updated for the next iteration,  $V_0^{i+1}$ :

$$I_{DN} - I_{DP} + I_{R_L} + I_{C_L} = 0$$

$$A_{N} + B_{N}V_{o}^{i+1} + A_{P} + B_{P}V_{o}^{i+1} + \frac{V_{o}^{i+1} - V_{SS}}{R_{L}} + C_{L}\frac{V_{o}^{i+1} - V_{o}^{i}}{\Delta t} = 0$$

$$V_{o}^{i+1} = \frac{V_{SS} + V_{o}^{i}\frac{R_{L}C_{L}}{\Delta t} - (A_{N} + A_{P})R_{L}}{1 + \frac{R_{L}C_{L}}{\Delta t} + (B_{N} + B_{P})R_{L}}$$

### Modeling 20GHz, 1V Coupled to 0.1μm & 0.25μm Inverters

-Output follows input but with reduced amplitude in 0.25
-Bit errors can still occur in larger device but may be less likely





0.25µm Output



# An Impulse-Response Based Methodology for Modeling Complex On-Chip Interconnect Networks: Random or Deterministic Inputs

#### Zeynep Dilli, Neil Goldsman, Akın Aktürk

Dept. of Electrical and Computer Eng. University of Maryland, College Park Experimental Chip for EM Coupling and Gate Current Measurements.

Designed at UMD Fabricated by MOSIS

Thousands of Metal Interconnect lines



• Objective: Investigate the response of a complex on-chip interconnect network to external RF interference or internal coupling between different chip regions

• Full-chip electromagnetic simulation: Too computationallyintensive

• Full-wave simulation possible for small "unit cell"s: Simple seed structures of single and coupled interconnects, combined to form the network.

• We have developed a methodology to solve for the response of such a network composed of unit cells with random inputs.



Sample unit cells for a two-metal process

- On-chip interconnects on lossy substrates: capacitively and inductively coupled to each other
  - Characterized with S-parameter measurements
  - Equivalent circuit models found by parameter-fitting
- For small interconnect unit cells, create an equivalent circuit model from EM simulation results/S-parameters.



• Lumped element model: Uses resistors and capacitors (Unit cells marked with red boxes in the figure).



• The interconnect network is a linear time invariant system: It is possible to calculate the output to any input distribution in space and time from the impulse responses.

**Characterize System by Response to Impulses** 

$$f[x,t] = \sum f_i[t] \Rightarrow F[x,t] = \sum F_i[t]$$
$$\Rightarrow F[x,t] = \sum_i \sum_j f_i[t_j] h_i[x,t-t_j]$$



#### **Response to a General Input from Impulse Responses**



Define the unit impulse at point x<sub>i</sub>:  $\delta[x-x_i] = \begin{cases} 1, x=x_i \\ 0, else \end{cases}$ 

We calculate the system's impulse response:

 $\delta[\mathbf{x}-\mathbf{x}_i]\delta[\mathbf{t}-\mathbf{0}] \longrightarrow \mathbf{h}_i[\mathbf{x},\mathbf{t}]$ 

Let an input f[x,t] be applied to the system. This input can be written as the superposition of time-varying input components  $f_i[t]=f[x_i,t]$ applied to each point  $x_i$ :

$$f[x,t] = \sum_{i} f_i[t]$$

We can write these input components  $f_i[t]$  as

$$f_i[t] = f[x,t]\delta[x-x_i]$$

Writing f<sub>i</sub>[t] as the sum of a series of time-impulses marching in time:

$$f_i[t] = \sum_j f[x,t] \delta[x-x_i] \delta[t-t_j]$$

### **Response to a General Input from Impulse Responses**



**Response to a General Input from Impulse Responses** 

$$f[t] = \sum f_i[t] \Rightarrow F[t] = \sum F_i[t]$$
$$\Rightarrow F[x,t] = \sum_i \sum_j f_i[t_j] h_i[x,t-t_j]$$



# **Characterize Impulse Response of Entire Chip**

Choose a spatial mesh and a time period

• Calculate the impulse response over all the period to impulse inputs at possible input nodes (might be all of them)

• The input values at discrete points in space and time can be selected randomly, depending on the characteristics of the interconnect network (coupling, etc.) and of the interference. Let

$$\alpha_{ij} \coloneqq f[x_i, t_j]$$
$$\Rightarrow F[t] = \sum_i \sum_j \alpha_{ij} h_i [x, t - t_j]$$

• Then we can calculate the response to any such random input distribution  $\alpha_{ij}$  by only summation and time shifting • We can explore different random input distributions easily, more flexible than experimentation

# **A Demonstration using SPICE**



• *Goal:* Simulate response at Point F3 to a discrete-time input given by the sum of two impulses at Point 2 and two at Point 5:

$$2\delta(x-x_2,t)+3\delta(x-x_2,t-200ns)$$

 $+3\delta(x-x_5,t-100ns)+\delta(x-x_5,t-400ns)$ 

# **A Demonstration using SPICE**

• Theoretically, the response at point F3 to this input  $2\delta(x-x_2,t) + 3\delta(x-x_2,t-200ns) + 3\delta(x-x_5,t-100ns) + \delta(x-x_5,t-400ns)$ 

is obtainable by the time-shifted sum of scaled impulse responses:

$$2h_{3_{2}}(t) + 3h_{3_{2}}(t - 200ns) + 3h_{3_{5}}(t - 100ns) + h_{3_{5}}(t - 400ns)$$



• Calculate this analytically from the simulated impulse responses and compare with simulation result

# **A Demonstration using SPICE**





# **Impulse Response and SPICE Agree**

Transient Response and Composite from Impulse Responses

Red: Simulated. Black: Composite



# **Interconnect Network Solver Outline**

- Developed an in-house network solver. Preliminary results presented at ISDRS'05, December 2005. More results to be presented in SISPAD 2006.
- Inputs: A 2-D or 3-D lumped network; input waveforms with the input locations indicated; locations that the user wishes to observe responses at.
- *Outputs:* Impulse responses at given output locations to impulses at given input locations; the composite output at given output locations to the input waveforms provided.
- Algorithm:
  - **1**. Read in network mesh structure, the input impulse locations, the output locations
  - 2. Set up the KCL-based system of difference equations for the mesh
  - **3.** For each impulse location, stimulate the system with a unit impulse
    - **1**. Solve for the time evolution of the voltage profile across the network
    - 2. Record the values at the set output points, creating impulse responses vs. time
  - 4. Use the full input waveforms together with calculated impulse responses to compose the full output at the requested output locations.
- Computational advantages:
  - Impulse responses calculated once used for system response to many inputs;
  - Impulse responses at only the desired points in the system need to be stored to calculate the output at those points for any input waveform.

# **Sample 3-D Network**



Only 5x5x2 mesh shown for simplicity. Not all vertical connections shown.

All nodes on the same level connected with an R//C to their neighbors.

All nodes on lowest level are connected with an R//C to ≩ground.

All nodes in intermediary levels are connected with an R//C to neighbors above and below.

# Impulse Response Solver Results: 11x11x5 Mesh

Solves for the response over the mesh using a system of differential equations derived from KCL equations.

Given here: Results for a 11x11x5 mesh.

*Input points:* (1,1,1) (bottom layer, southwest corner), (11,20,5) (near north edge center, topmost layer).

Sample output points (5,5,1) (bottom layer, southwest of center); (11,11,3) (center layer, exact center); (20,2,5) (top layer, southeast of center).



# Impulse Response Solver Results: : 11x11x5 Mesh

#### Sample impulse response over all five layers:



Unit impulse at point (11,20,5).

The animation shows the impulse response until t=6 nsec with 1 nsec increments.

Note that this result is from a network with all horizontal connections resistive only.

# Impulse Response Solver Results : 11x11x5 Mesh

Sample impulse responses shown one layer at a time (click to play; horizontal connections resistive only.):

Layer 1

Impulse at (1,1,1)



#### Impulse at (11,20,5)



# **Impulse Response Solver Results : 11x11x5 Mesh**

Sample impulse responses shown one layer at a time (click to play; horizontal



Impulse at (11,20,5)



# Impulse Response Solver Results : 11x11x5 Mesh

Sample impulse responses shown one layer at a time (click to play; horizontal connections resistive only.):

Layer 5: Note that the north-south resistors are smaller than east-west resistors; hence the uneven response distribution.

Impulse at (1,1,1)



Impulse at (11,20,5)



# **Impulse Response Solver Results: Clock Tree**

An example three-metal-layer interconnect network representation. The connections are resistive and/or capacitive as required.



#### Impulse Response Solver Results: 50x50x3 Mesh



# **Current work**

• The method is flexible enough for mesh expansion; we are investigating computationally efficient ways of solving much larger mesh networks.

• We are developing unit cells modeling physical interconnect structures:

• With appropriate unit cells, we can investigate the full networks of 3-D integrated chips

• We plan to use EM modeling tools and S-parameter measurements and extraction

• Example goal application: Determine which locations are most vulnerable for substrate and ground/VDD noise-sensitive subcircuits included in 3-D integrated system with different types of circuit networks on the individual layers (e.g. communication on top layer, data storage in the middle, data processing at the bottom...)

# Conclusion

• Developed a method to model and investigate the response of a complex on-chip interconnect network to external RF interference or to internal coupling between different chip regions or subcircuits.

- Computational advantages:
  - Impulse responses calculated once characterize system
  - System response arbitrary input can then be predicted.
  - System response to deterministic, random, Gaussian, etc. can be easily modeled.

• The same unit cells can be combined for many interconnect layouts; thus flexibility in the systems that can be investigated;

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